

Too Hot to Test? For Leading-edge SoC and Heterogenous Integrated IC Stack

Markus Kindler | Ferdinand Wimmer (ATT Systems) and Amy Leong (FormFactor Inc)

December 2021







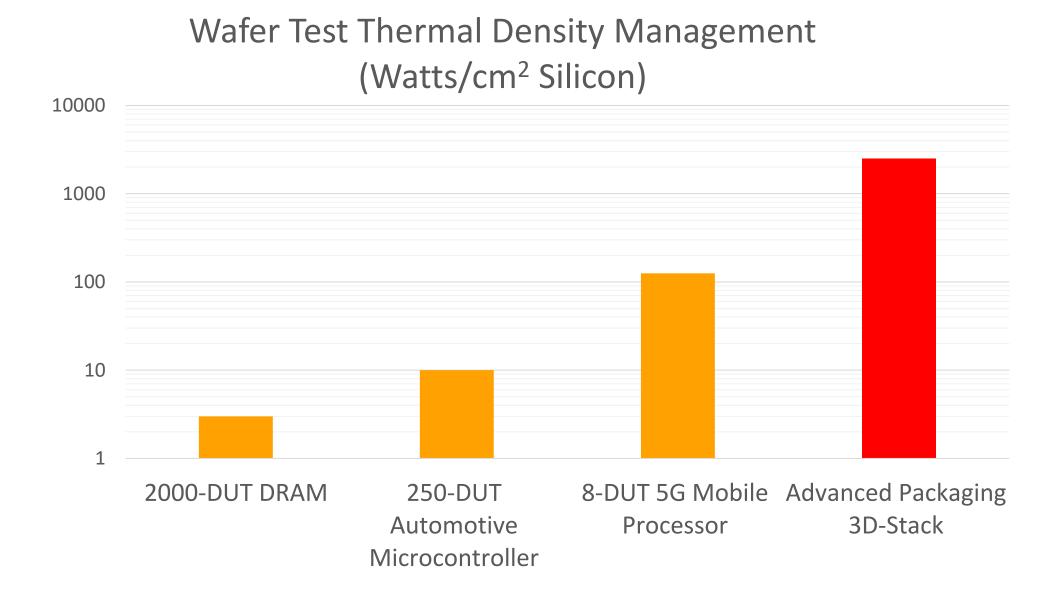
Wafer Test Trends – Too Hot To Test?

- Testing of high power IC's (i.e. AI/Processors) + 1TD DRAM is approaching an inflection point
- High power density of DUT's need better thermal chuck to dissipate the peak power
- Standard wafer chucks are not able to sense temp increase and to dissipate the applied energy, resulting in
 - device damage
 - burned probes
 - inaccurate test results
- Heterogenous integration will further increase power densities by >10X
 - processor + HBM (8 16 die) stacked on a base wafer
- Active temperature control solutions are required
 - Low Thermal Resistance
 - MultiSense Temp Control Liquid Cooling
- ATT's Low Thermal Resistance (LTR) chuck technology addresses these challenges





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What is a Thermal Chuck?

Air Cooled



-40C to +200C

-60C to +200C

Modular Base Chuck System





Universal chuck and controller

2 independent cooling circuits

+20C to +200C without chiller

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Liquid Cooled



-20C to +200C

-40C to +200C

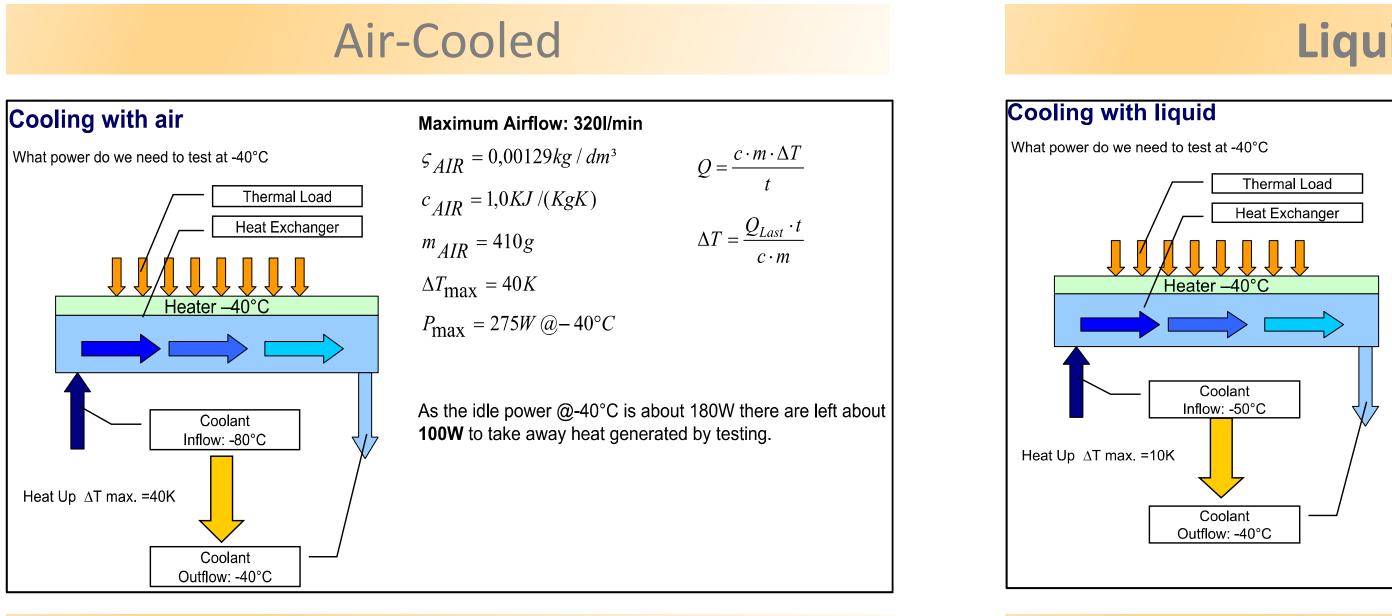
-60C to +200C







High Power Testing – Why Liquid Cool?



Max. Cooling Capacity is low at 275W

Effective Cooling Capacity is low at 100W

∆T high – impact on temp. uniformity

High air-flow@high pressure

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Liquid-Cooled

Coolant Flow:10l/min $\varsigma_{ZT130} = 1.8 kg / dm^3$ $c_{ZT130} = 1,1KJ/(KgK)$ $m_{Zt130} = 18000g$ $\Delta T_{\rm max} = 10K$ $P_{\rm max} = 3300W$

For 200W and 600W heat load applied by testing following ratios are calculated

$P_{load} = 200W$	$P_{load} = 600W$
$c_{ZT130} = 1,1KJ/(KgK)$	$c_{ZT130} = 1,1KJ/(KgK)$
$m_{Zt130} = 18000g$	$m_{Zt13m} = 18000g$
$\Delta T = \frac{Q_{Last} \cdot t}{c \cdot m} = 1,15K$	$\Delta T = \frac{Q_{Last} \cdot t}{c \cdot m} = 2,35K$

Liquid cooled systems are the tools of choice due to the high cooling power and better temp. uniformity!

Max. Cooling Capacity is high at >3000W

 $\Delta T \log - \log impact on temp. uniformity$

Reasonable cooling fluid consumption

Wider temp range might require other fluids



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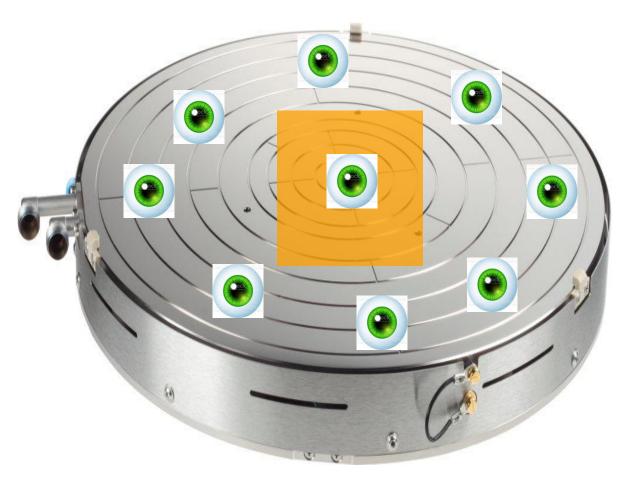


Active Temperature Control – MultiSense

Full Wafer Contact

100x100mm





- Full Wafer Contact: Uniformly distributed thermal load one control sensor is sufficient Smaller Contact Areas: Require multiple control sensors to detect temp changes Number of built-in sensors is limited due to chuck complexity – total of 9 control sensors • MultiSense AddOn sensors is scalable, currently up to 21 sensors

- Requires advanced temp control algorithms

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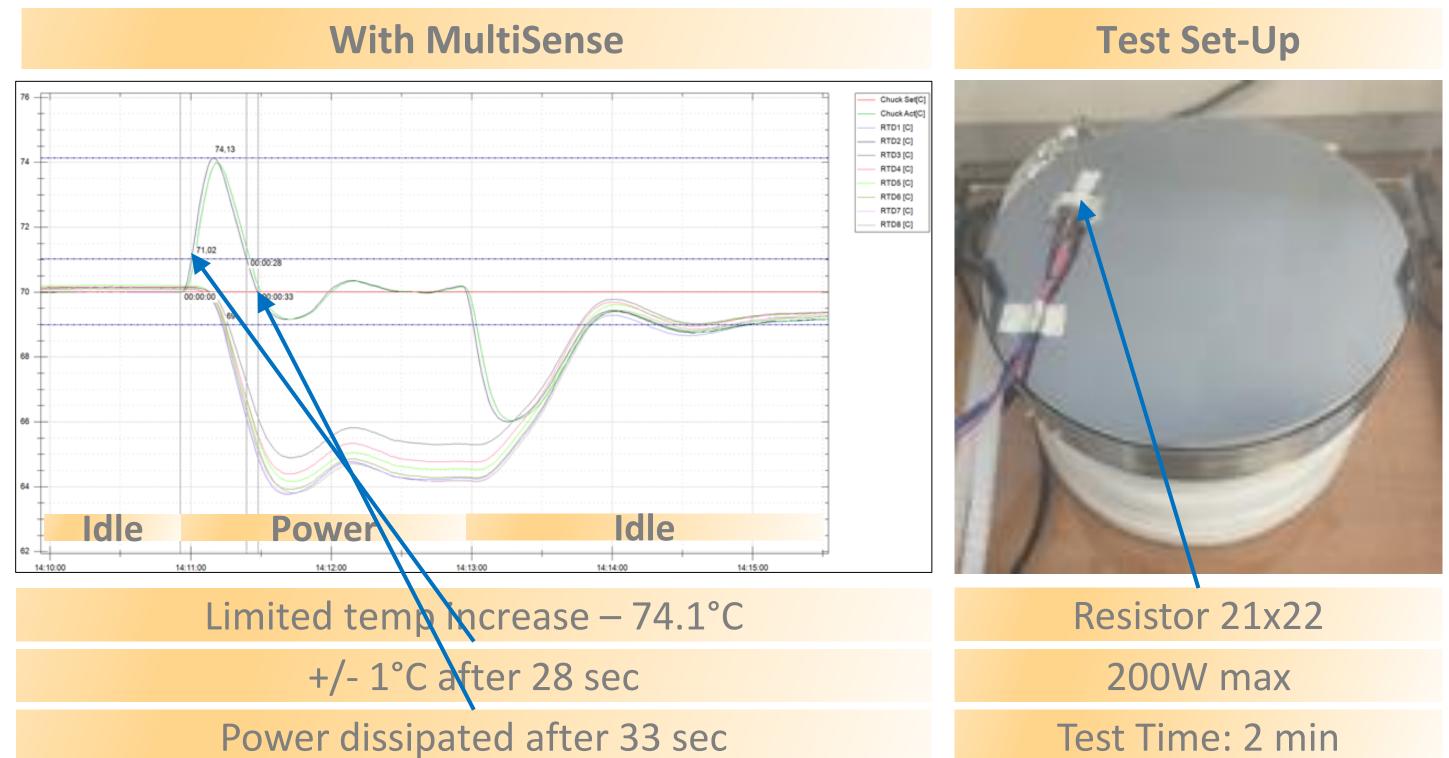
20x20mm





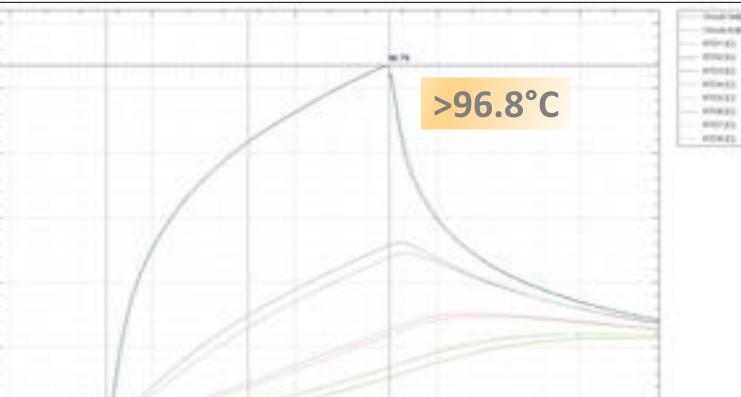
MultiSense vs. No MultiSense

+70°C, 200W, 21x22mm contact area, 2 min test time, liquid cooled



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Idle



Without MultiSense

---minute 1000 all with the

Idle

Uncontrolled temp rise to >96°C No temp change detection **No Active Temp Control**

Power



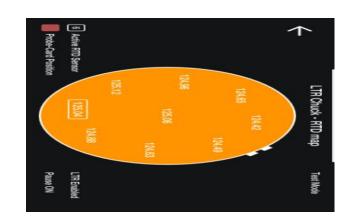


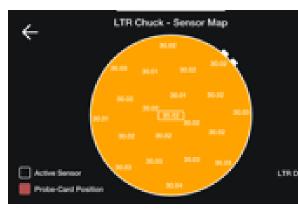


ATT's Low Thermal Resistance (LTR) Chuck Technology

- Developed for High Power (HP) and High Accuracy (HA) Applications
- Al devices, GPU's, CPU's, Stacked Memories, Heterogenous integrated devices
- Low Thermal Resistance chuck design w/ MultiSense Active Temp Control
- Scalable number of temp control sensors (e.g. 9 or 21 sensors)
- Scalable cooling power options, upgradeable as needed (600W to >20KW)

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Application Examples

Full Wafer Contact DRAM, Flash, HBM



Contact Area: Large Parallelism: High

Power/Die: Low Density: Low (3W/cm²)

Heat transfer: up to 2000W Temp. Range: -40°C to +125°C



Contact Area: Medium Parallelism: Medium/Low

Heat transfer: up to 1000W Temp. Range: -40°C to +125°C

Power/Die: Medium/High Density: Medium (10W/cm²)

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100x100mm E.g. Microcontroller

20x20mm E.g. 5G or GPU devices



Contact Area: Small Parallelism: Low

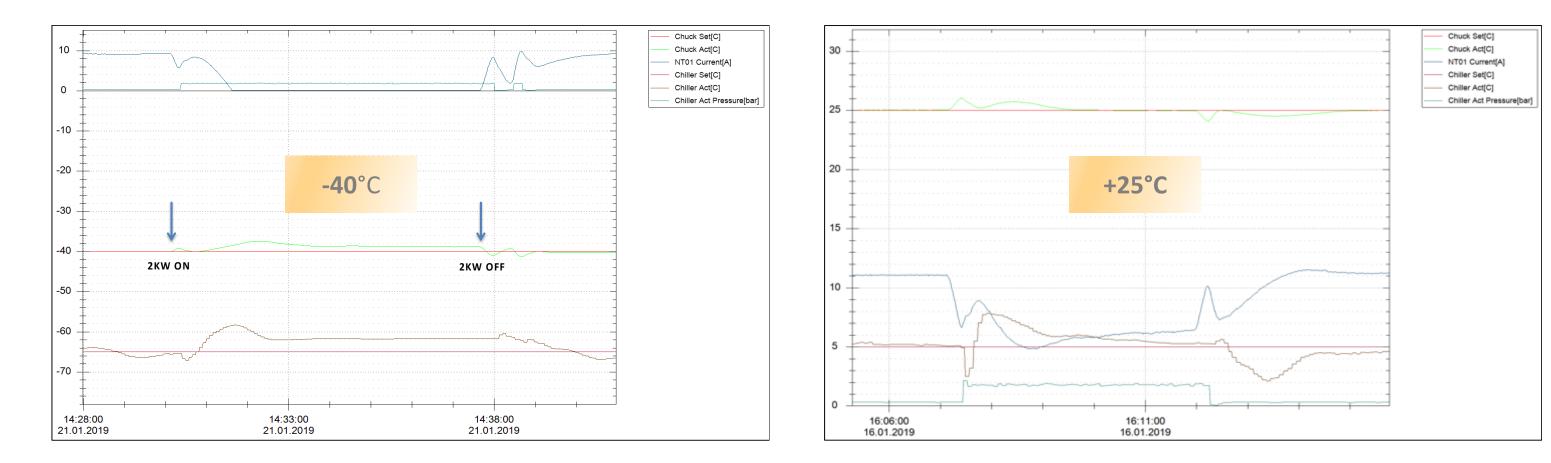
Power/Die: High **Power Density: High (125W/cm2)**

Heat transfer: up to 500W Temp. Range: -40°C to +125°C





Customer Case Study – Full Wafer Contact, 2000W



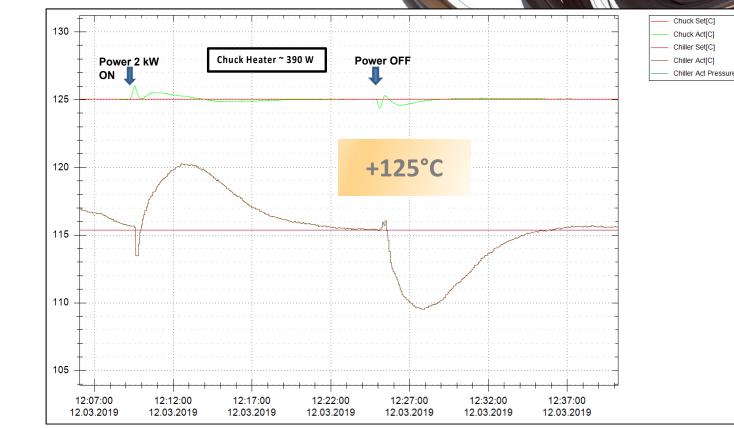
Full Wafer Contact – High Bandwidth Memory Testing

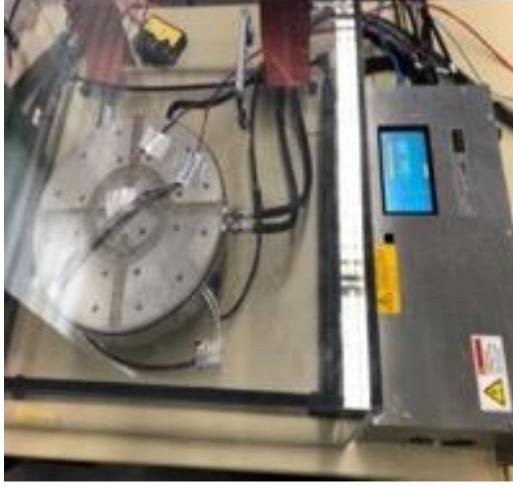
Applied power of 2000 Watts, uniformly distributed across the chuck

Liquid Chiller, -40°C, +25°C and +125°C

Chuck system is able to dissipate 2000W at all three temperatures

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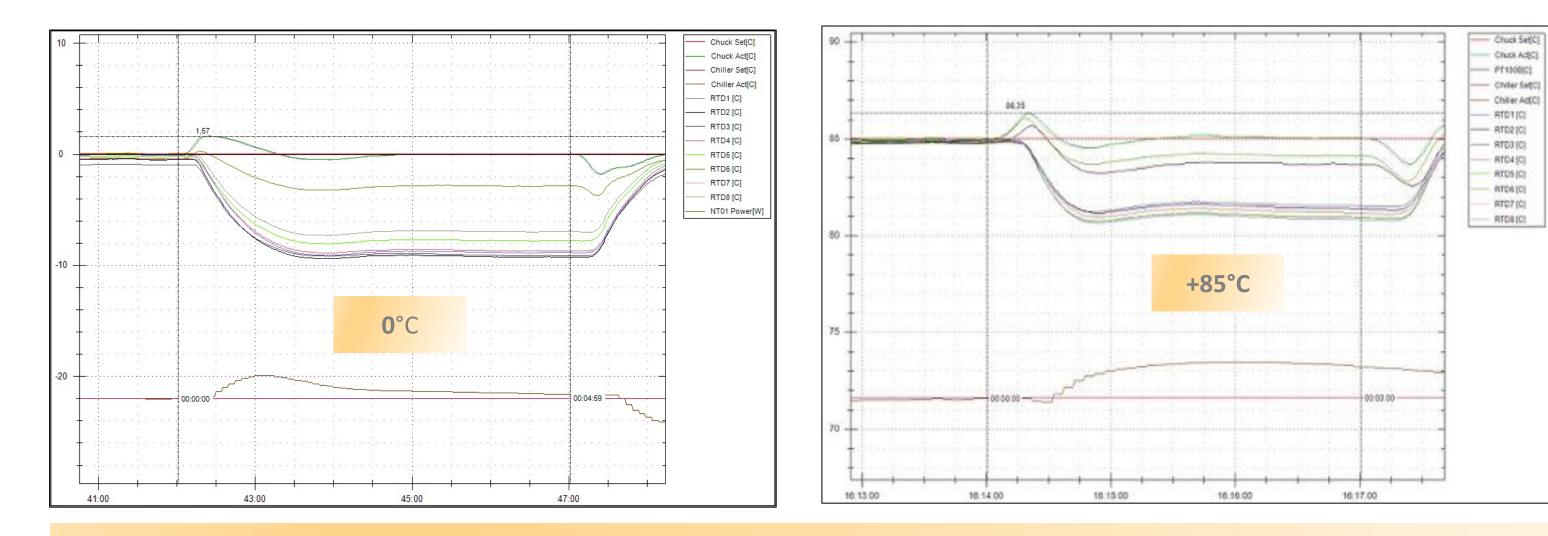








Customer Study – 100x100mm, 400W



100x100mm contact area – Automotive microcontroller

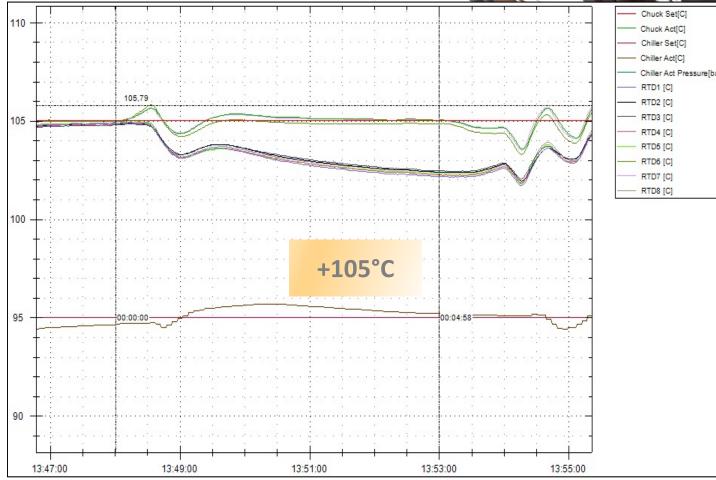
Applied power of 400 Watts

Liquid Chiller, 0°C, +85°C and +105°C

Chuck system is able to dissipate 400W within a +/- 2°C temperature range







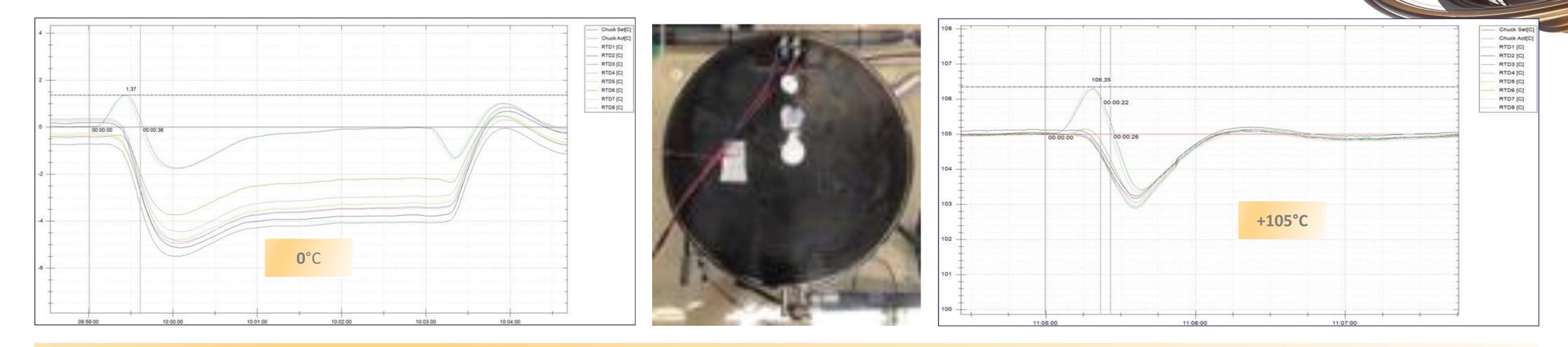
HYBRID

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Customer Study – 21x20mm – 160W



21x20mm contact area – 5G Device

Applied power of 160 Watts

Liquid Chiller, 0°C and +105°C

Chuck system is able to dissipate 400W within a +/- 2°C temperature range

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Summary

- Increasing thermal challenges to test leading-edge SoC, full-wafer memory, and heterogenous integrated device require Liquid Cooled wafer chuck systems for high power dissipation
- Customer case study showed ATT's Low Thermal Resistance (LTR) chuck is doable for
 - Full Wafer Contact up to 2KW
 - 100x100mm up to 400W higher power possible with stronger chillers
 - 21x20mm up to 160W higher power possible with stronger chillers
- Wafer test requirements are changing dynamically Power densities, Parallelism, IC complexity
- ATT is working on new chuck concepts addressing future requirements Please contact us for more details

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FORWARD AS ONE

Thank You







